

Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 12732-061002	Application No. 10/792,132
Information Disclosure Statement by Applicant (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Taketomi Asami et al.	
		Filing Date March 4, 2004	Group Art Unit

U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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	AB	2002/0014625 A1	02/07/2002	Asami et al.			
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Examiner Signature

JOSEPH NGUYEN

Date Considered

11/09/05

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	ABB	6,690,068	02/10/2004	Yamazaki et al.			

Foreign Patent Documents or Published Foreign Patent Applications

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							Yes	No
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